Nonlinear vibrations of M/NEMS resonant sensors Najib KACEM^{1;2}, Sébastien BAGUET¹, Régis DUFOUR¹, Sébastien HENTZ² ¹ LaMCoS, INSA-Lyon, CNRS UMR5259 ² CEA/LETI - MINATEC, Grenoble

Context

- Collaboration with CEA LETI, applied research center for microelectronics.
- M/NEMS (Micro/Nano Electro-Mechanical Systems) sensors are used for GPS navigation, camcorder stabilization, airbag, video games, missile guidance, ...
- Scaling MEMS down to NEMS makes the dynamic behavior nonlinear.
- Need for a lightweight and easy-to-use model for MEMS designers.

Objectives

- Nonlinear dynamics of MEMS resonators (numerical and analytical solutions).
- Strategies for enhancing the performances.





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MEMS accelerometer sensor

- Resonator = vibrating beam + activation/detection electrodes.
- Continuous voltage Vdc for bending + alternating harmonic voltage Vac at fundamental frequency
- The variation of the axial load (inertia of the mass subjected to acceleration) induces a variation of the fundamental frequency of the resonator
- The measurement of the variation in frequency leads to the axial load (ie acceleration)



SEM image of the resonant accelerometer





Variation of fundamental frequency due to axial load N

Multiphysics model

Euler-Bernoulli beam

- Mechanical and electrostatic nonlinearities





Numerical simulations

- Modal decomposition
- Harmonic Balance (HBM) : decomposition in Fourier series Nonlinear differential problem ⇒ Nonlinear algebraic problem
- Asymptotic Numerical Method (MAN) : robust continuation of Nonlinear solutions with respect to a varying parameter





Experimental validation



SEM



sample resonators

SEM image of the resonator

Performance enhancement

The resonator can be driven beyond the critical amplitude by cancelling out the nonlinearities Pull-in retarding under superharmonic excitation



Response curve of the resonator : transverse displacement vs. frequency Influence of the electrostatic force on the nonlinear dynamic behavior

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Analytical solution

- Perturbation technique : averaging Closed-form expressions of the critical amplitude and the dynamic pull-in amplitude
- Simplified model for fast M/NEMS design



Future work

Resonator with 2 electrodes for actuation and sensing Extension to resonant gyroscope with axial parametric excitation

Cantilever beam for mass detection

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